

SCOPE OF ACCREDITATION TO ISO/IEC 17025:2017 & ANSI/NCSL Z540-1-1994

MASTER GAGE & TOOL CO. 112 Maplewood Street Danville, VA 24540

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CALIBRATION

Valid To: June 30, 2024 Certificate Number: 2200.01

In recognition of the successful completion of the A2LA evaluation process, accreditation is granted to this laboratory to perform the following calibrations^{1, 6}:

I. Dimensional

Parameter/Equipment	Range	CMC ^{2, 4} (±)	Comments
Calipers	Up to 60 in	(14 + 7.3L + 0.6R) µin	Gage blocks, ring gages and pins; IT 1002
Calipers ³	Up to 60 in	$(13 + 30L + 0.6R) \mu in$	Gage blocks, ring gages and pins; OIT 1002
Caliper and Depth Micrometer Masters	(0.001 to 6) in	$(88 + 2.2L) \mu in$	Gage blocks, amp and probe; IT 1035
Gage Blocks	Up to 4 in (> 4 to 13) in	$(3 + 1.5L) \mu in$ (5 + 0.8L) μin	Master gage blocks & P&W Universal Labmaster™; IT 1060
Coordinate Measuring Machine ³ (CMM) –			
X, Y, Z Axis Linear Accuracy	(1 to 48) in	$(7 + 30L + 0.6R) \mu in$	Verification of CMMs using gage blocks &
Squareness	(1 to 48) in	$(66 + 0.6R) \mu in$	granite squares; OIT 1049

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Parameter/Equipment	Range	CMC ^{2, 4} (±)	Comments
Cylindrical Gages – Plug: Outside Diameter –			
Up to XXX	(0.001 to 9) in (> 9 to 13) in	(6.4 + 3.5 <i>D</i>) μin (8.4 + 0.6 <i>D</i>) μin	Gage blocks & P&W Universal Labmaster [™] ; IT 1003
Ring: Inside Diameter – Up to XX XXX	(0.04 to 14) in (0.04 to 14) in	(14 + 1.5 <i>D</i>) μin (8.5 + 0.6 <i>D</i>) μin	Class XXX Master rings or gage blocks & P&W Universal Labmaster [™] ; IT 1021
Cylindrical Gages ³ – Plug: Outside Diameter – Up to X	(0.001 to 9) in	(16 + 29 <i>D</i>) μin	Gage blocks & P&W used serviceable material™; OIT 1003
Glass Scales, Precision	(0.001 to 12) in	(63 + 4 <i>L</i>) μin	Vision system; IT 1044
Height Gages	Up to 60 in	(54 + 6.7L + 0.6R) µin	Gage blocks; IT 1010
Height Gages ³	Up to 60 in	(82 + 29L + 0.6R) µin	Gage blocks; OIT 1010
Indicators	Up to 4 in	$(4 + 17L + 0.6R) \mu in$	Indicator stand & grade 2 gage blocks IT 1007
Indicators ³	Up to 4 in	$(4 + 31L + 0.6R) \mu in$	Indicator stand & grade 2 gage blocks OIT 1007
Length Standards	(0.001 to 6) in	(20 + 2.1 <i>L</i>) μin	Gage blocks with P&W Universal Labmaster [™] ; IT 1012
	(> 6 to 34) in	(42 + 8 <i>L</i>) μin	Gage blocks with amp & probe; IT 1012

Dogogo et au/E qui am out	Dance	CMC2.4(1)	Comments
Parameter/Equipment	Range	$CMC^{2,4}(\pm)$	Comments
Levels – Level Vial Setting	(2 to 24) in	130 μin	Surface plate & gage blocks; IT 1013
Micrometers –			Gage blocks & spheres;
Outside Depth Inside Bore/Holematic	Up to 24 in Up to 12 in Up to 12 in Up to 9 in	(20 + 7L + 0.6R) µin $(31 + 5.8L + 0.6R)$ µin $(33 + 6.4D + 0.6R)$ µin $(48 + 4.2D + 0.6R)$ µin	IT 1017 IT 1006 IT 1011 IT 1011
Micrometers ³ –			Gage blocks & spheres;
Outside Depth Inside Bore/Holematic	Up to 24 in Up to 12 in Up to 12 in Up to 9 in	$(10 + 30L + 0.6R) \mu in$ $(17 + 30L + 0.6R) \mu in$ $(20 + 29L + 0.6R) \mu in$ $(15 + 30D + 0.6R) \mu in$	OIT 1017 OIT 1006 OIT 1011 OIT 1011
Optical Comparators & Vision Systems ³ –			
X, Y, Z Axis Linear Accuracy	(0.001 to 12) in	(57 + 0.6 <i>R</i>) μin	Glass standard; OIT 1045
Microscopes/Reticles ³ – Length	(0.001 to 4) in	(98 + 0.6 <i>R</i>) μin	Glass standard; OIT 1050
Pin Gages & Sets	(0.001 to 2) in	(26 + 2.4 <i>D</i>) μin	Laser micrometer & master plugs or gage blocks & bench micrometer; IT 1020
Pin Gages & Sets ³	(0.001 to 2) in	(34 + 25D) μin	Laser micrometer & master plugs or gage blocks & bench micrometer; OIT 1020
Radius Gages	Up to 1 in	200 μin	Vision system; IT 1023

Parameter/Equipment	Range	CMC ^{2, 4} (±)	Comments
Plain Taper Gages –			Gage blocks, pins, master plugs, bench micrometer & comparator;
Outside Diameter – Minimum Truncations: Length Steps	(0.05 to 6) in (0.2 to 3) in	$(30 + 4.1D) \mu in$ (50 + 1.3L) μin	IT 1031
Inside Diameter – Minimum Truncations: Length Steps	(0.2 to 3) in	160 μin (50 + 1.3 <i>L</i>) μin	IT 1032
Protractor –			
Bevel Digital	(0 to 90)° (0 to 90)°	$0.06^{\circ} + 0.6R$ $0.05^{\circ} + 0.6R$	Vision system or gage blocks & sine bar; IT 1022
Rules	Up to 24 in (> 24 to 72) in	(57 + 6 <i>L</i>) μin (150 + 9 <i>L</i>) μin	CMM or vision system IT 1024
Spheres –			
Diameter & Sphericity	(0.04 to 2) in	(46 + 4 <i>D</i>) μin	Gage blocks & bench micrometer; IT 1036
Snap Gages – Plain Anvils Fixed or Adjustable Outside Diameter	(0.01 to 12) in	$(40 + 5L) \mu in$	Gage blocks & pins; IT 1057
Snap Gages ³ – Plain Anvils Fixed or Adjustable Outside Diameter	(0.01 to 12) in	(32 + 28 <i>L</i>) μin	Gage blocks & pins; OIT 1057

Parameter/Equipment	Range	$CMC^{2, 4}(\pm)$	Comments
Straight Thread Gages –			Thread wires, optical comparator, gage blocks & Supermicrometer TM ;
Outside Diameter: Simple Pitch Diameter	(0.04 to 3) in (> 3 to 9) in	(64 + 6.7 <i>D</i>) μin (57 + 9 <i>D</i>) μin	IT 1033
Major Diameter: Pitch, Lead, & Flank Angles	(0.04 to 9) in	(56 + 4.5 <i>D</i>) μin 0.09° (6")	
Inside Diameter: Minor Diameter	(0.04 to 3) in	(210 + 27 <i>D</i>) μin	IT 1034
Straight Thread Gages ³ –			
Outside Diameter: Simple Pitch Diameter	(0.04 to 3) in (> 3 to 9) in	(62 + 10 <i>D</i>) μin (55 + 12 <i>D</i>) μin	Thread wires, optical comparator, &
Major Diameter	(0.04 to 9) in	(57 + 11 <i>D</i>) μin	Supermicrometer TM ; OIT 1033
Surface Finish –			Master pad & comparator;
Gages	Ra/Ry	$(3.8 + 0.6R) \mu in$	IT 1028
Specimens	Ra/Ry	3.4 µin	IT 1059
Contour Measuring Instruments ³ –			
Surface finish	Ra/Ry	$(3.8 + 0.6R) \mu in$	Master surface finish pad per OIT 1028
Detector Displacement – Z Axis Straightness Length – X Axis	(-30 to +30) mm Up to 200 mm Up to 200 mm	$(0.22 + 0.01L + 0.6R) \mu m$ $0.46 \mu m + 0.6R$ $(0.36 + 0.012L + 0.6R) \mu m$	Straight edge, gage blocks & pitch gage per OIT 1069

Parameter/Equipment	Range	CMC ^{2, 4} (±)	Comments
Taper Thread Gages –			
Outside Diameter: Length of Step & Size at Gage Plane	(0.05 to 3) in (3 to 10) in	(46 + 9.5 <i>L</i>) μin (56 + 6.1 <i>L</i>) μin	Micrometer Supermicrometer TM ; IT 1037
Inside Diameter: Ring Thickness & Standoff to Master Plug	(0.065 to 3) in	(230 + 2D) μin (50 + 1.3L) μin	Master plugs, IT 1038
Thread Wires	All pitches, 60°	10 μin	P&W Universal Labmaster TM , IT 1064
Bench Micrometers –			
Linearity	Up to 1 in	$(25 + 0.6R) \mu in$	Gage blocks, force
Force	Up to 40 oz	0.2 % of reading	gage, IT 1005
Bench Micrometers ³ –			
Linearity	Up to 1 in	$(25 + 0.6R) \mu in$	Gage blocks, force
Force	Up to 40 oz	0.2 % of reading	gage; OIT 1005
Feeler Gages	Up to 0.2 in	48 μin	Bench micrometer; IT 1008
Feeler Gages ³	Up to 0.2 in	51 μin	Bench micrometer; OIT 1008
Laser Bench Micrometer	Up to 2 in	$(14 + 6.4D + 0.6R) \mu in$	Gage pins; IT 1067
Laser Bench Micrometer ³	Up to 2 in	$(15 + 3.5D + 0.6R) \mu in$	Gage pins; OIT 1067

II. Dimensional Testing/Calibration¹ – Fixtures & Gauging

Parameter/Equipment	Range	CMC ^{2, 4} (±)	Comments
Length ⁵ – Workpieces & Gage Fixtures			IT 1042
1D (X Axis) 1D (Y Axis) 1D (Z Axis) 2D (Axis X & Y)	Up to 12 in Up to 8 in Up to 6 in Up to 12 in	(60 + 6.8 <i>L</i>) μin (63 + 3.7 <i>L</i>) μin (60 + 8.4 <i>L</i>) μin (98 + 6.2 <i>L</i>) μin	Vision systems
3D	Up to (24 in x 36 in x 24 in)	$(54 + 7.6L) \mu in$	CMM

III. Mechanical

Parameter/Equipment	Range	CMC ² (±)	Comments
Torque ³ –			
Wrenches	Up to 600 ft·lbf Up to 3000 in·lbf	0.36 % of reading 0.30 % of reading	Torque calibrator;
Handles/Screwdriver	Up to 120 in·lbf	0.58 % of reading	IT/OIT 1063
Indirect Verification of Vickers Hardness Testers ³ – Up to 1000 gf	50 gf 100 gf 300 gf 500 gf 1000 gf	38 HV 26 HV 14 HV 12 HV 9.8 HV	ASTM E-384; OIT 1066
Indirect Verification of Knoop Hardness Testers ³ – Up to 1000 gf	50 gf 100 gf 300 gf 500 gf 1000 gf	24 HK 17 HK 27 HK 14 HK 16 HK	ASTM E-384; OIT 1066
Indirect Verification of Brinell Hardness Testers ³ –			
HBW 10/500/(10 to 15) HBW 10/3000/(10 to 15) HBW 10/3000/(10 to 15)	(100 to 200) HBW (300 to 400) HBW (500 to 600) HBW	4.7 HBW 5.6 HBW 8.1 HBW	ASTM E10, E110; OIT 1047

Parameter/Equipment	Range	CMC ² (±)	Comments
Indirect Verification of Rockwell & Rockwell Superficial Testers ³	HRA: Low Medium High	1.2 HRA 1.2 HRA 1.2 HRA	Indirect verification per method ASTM E18 with test blocks; OIT 1047
	HRBW: Low Medium High	1.7 HRBW 1.7 HRBW 1.4 HRBW	
	HRC: Low Medium High	0.98 HRC 0.8 HRC 0.6 HRC	
	HRD: Low Medium High	1.2 HRD 1.2 HRD 0.64 HRD	
	HREW: Low Medium High	1.3 HREW 1.3 HREW 1.3 HREW	
	HRFW: Low Medium High	1.3 HRFW 1.3 HRFW 1.3 HRFW	
	HRGW: Low Medium High	1.4 HRGW 1.6 HRGW 1.3 HRGW	
	HRHW: Low High	1.3 HRHW 1.2 HRHW	
	HRKW: Low Medium High	1.5 HRKW 1.5 HRKW 1.4 HRKW	

Parameter/Equipment	Range	CMC ² (±)	Comments
Parameter/Equipment Indirect Verification of Rockwell & Rockwell Superficial Testers ³ – (cont)	HR15N: Low Medium High HR30N: Low Medium High HR45N: Low Medium High HR15TW: Low Medium High HR30TW: Low Medium High	1.6 HR15N 1.3 HR15N 0.98 HR15N 1.3 HR30N 1.3 HR30N 0.96 HR30N 1.3 HR45N 1.2 HR45N 0.8 HR45N 2 HR15TW 1.4 HR15TW 1.4 HR15TW 1.4 HR15TW 1.4 HR30TW 1.4 HR30TW	Indirect verification per method ASTM E18 with test blocks; OIT 1047
	High HR45TW: Low Medium High HRRW: Low High	1.4 HR30TW 2.0 HR45TW 1.4 HR45TW 1.3 HR45TW 1.2 HRRW 1.2 HRRW	

¹ This laboratory offers commercial calibration service, field calibration service and dimensional/calibration services.

² Calibration and Measurement Capability Uncertainty (CMC) is the smallest uncertainty of measurement that a laboratory can achieve within its scope of accreditation when performing more or less routine calibrations of nearly ideal measurement standards of nearly ideal measuring equipment. CMCs represent expanded uncertainties expressed at approximately the 95 % level of confidence, usually using a coverage factor of k = 2. The actual measurement uncertainty of a specific calibration performed by the laboratory may be greater than the CMC due to the behavior of the customer's device and to influences from the circumstances of the specific calibration.

- ³ Field calibration service is available for this calibration. Please note the actual measurement uncertainties achievable on a customer's site can normally be expected to be larger than the CMCs found on the A2LA Scope. Allowance must be made for aspects such as the environment at the place of calibration and for other possible adverse effects such as those caused by transportation of the calibration equipment. The usual allowance for the uncertainty introduced by the item being calibrated, (e.g. resolution) must also be considered and this, on its own, could result in the actual measurement uncertainty achievable on a customer's site being larger than the CMC.
- ⁴ In the statement of CMC, *L* is the numerical value of the nominal length of the device measured in inches, or in mm for metric units; *R* is the resolution of the device under test in micro inches, or in micro meter for metric units; *D* is the numerical value of the nominal diameter of the device measured in inches.
- ⁵ This laboratory meets R205 *Specific Requirements: Calibration Laboratory Accreditation Program* for the types of dimensional tests listed above and is considered equivalent to that of a calibration.
- ⁶ This scope meets A2LA's *P112 Flexible Scope Policy*.



Accredited Laboratory

A2LA has accredited

MASTER GAGE & TOOL CO.

Danville, VA

for technical competence in the field of

Calibration

This laboratory is accredited in accordance with the recognized International Standard ISO/IEC 17025:2017 General requirements for the competence of testing and calibration laboratories. This laboratory also meets the requirements of ANSI/NCSL Z540-1-1994 and R205 – Specific Requirements: Calibration Laboratory Accreditation Program. This accreditation demonstrates technical competence for a defined scope and the operation of a laboratory quality management system (refer to joint ISO-ILAC-IAF Communiqué dated April 2017).

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Presented this 14th of April 2022.

Vice President, Accreditation Services
For the Accreditation Council
Certificate Number 2200.01
Valid to June 30, 2024

For the calibrations to which this accreditation applies, please refer to the laboratory's Calibration Scope of Accreditation.